## 數位反射式光彈法於長銲鋼軌殘留應力之量測 張奇偉,林鎮華,鞠志琨,簡孝宜 土木工程學系 建築與設計學院 ccw@chu. edu. tw

## 摘要

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and compared with the prestress value applied to the long welded rail.

關鍵字:Reflection Photoelasticity, Digital discrete image processing, Residual Stress